502456644 08/13/2013

PATENT ASSIGNMENT

Electronic Version v1.1
Stylesheet Version v1.1

SUBMISSION TYPE:	CORRECTIVE ASSIGNMENT
NATURE OF CONVEYANCE:	Corrective Assignment to correct the Nature of Conveyance from an "Assignment" to "Security Agreement" previously recorded on Reel 026842 Frame 0929. Assignor(s) hereby confirms the the original document submitted was a "Security Agreement".

CONVEYING PARTY DATA

Name	Execution Date
MOLECULAR IMPRINTS, INC.	09/01/2011

RECEIVING PARTY DATA

Name:	CANON INC.
Street Address:	30-2 Shimomaruko 3-chome
City:	Ohta-ku, Tokyo
State/Country:	JAPAN
Postal Code:	146-8501

PROPERTY NUMBERS Total: 110

Property Type	Number
Patent Number:	7136150
Patent Number:	7140861
Patent Number:	7019835
Patent Number:	7785526
Patent Number:	7122079
Patent Number:	7323130
Patent Number:	7309225
Patent Number:	7105452
Patent Number:	7252715
Patent Number:	7036389
Patent Number:	6982783
Patent Number:	7244386
Patent Number:	7252777

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Patent Number:	7041604
Patent Number:	7256131
Patent Number:	7282550
Patent Number:	7939131
Patent Number:	6990870
Patent Number:	7241395
Patent Number:	7547504
Patent Number:	7186656
Patent Number:	7205244
Patent Number:	7635445
Patent Number:	7292326
Patent Number:	7630067
Patent Number:	7798801
Patent Number:	7636999
Patent Number:	7170589
Patent Number:	7811505
Patent Number:	7281919
Patent Number:	7307118
Patent Number:	7298456
Patent Number:	7338275
Patent Number:	7727453
Patent Number:	7420654
Patent Number:	7316554
Patent Number:	7665981
Patent Number:	7387508
Patent Number:	7803308
Patent Number:	7259102
Patent Number:	7759407
Patent Number:	7670534
Patent Number:	7837921
Patent Number:	7279113
Patent Number:	7357876
Patent Number:	7906058
Patent Number:	7224443
Patent Number:	7037639

	7261831
Patent Number:	7906180
Patent Number:	7491637
Patent Number:	7691313
Patent Number:	7670529
Patent Number:	7670530
Patent Number:	7323417
Patent Number:	7635263
Patent Number:	7699598
Patent Number:	7780893
Patent Number:	7547398
Patent Number:	7462028
Patent Number:	7802978
Patent Number:	7854867
Patent Number:	7641840
Patent Number:	7473090
Patent Number:	6926929
Patent Number:	7670953
Patent Number:	7906274
Patent Number:	7837907
Patent Number:	6932934
Patent Number:	7845931
Patent Number:	7077992
Patent Number:	6900881
Patent Number:	7708926
Patent Number:	7795132
Patent Number:	6908861
Patent Number:	7071088
Patent Number:	7027156
Patent Number:	7070405
Patent Number:	6916584
Patent Number:	6936194
Patent Number:	6871558
Patent Number:	7785096
Patent Number:	7927541

	6929762
Patent Number:	7019819
Patent Number:	7880872
Patent Number:	7874831
Patent Number:	6980282
Patent Number:	7931846
Patent Number:	7858528
Patent Number:	7132225
Patent Number:	7910042
Patent Number:	7943081
Patent Number:	7452574
Patent Number:	7947608
Patent Number:	6805054
Patent Number:	7179396
Patent Number:	7396475
Patent Number:	6951173
Patent Number:	7442336
Patent Number:	7179079
Patent Number:	7150622
Patent Number:	7531025
Patent Number:	7270533
Patent Number:	7768624
Patent Number:	7815824
Patent Number:	7261830
Patent Number:	7090716
Patent Number:	7157036
Patent Number:	7122482

CORRESPONDENCE DATA

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	093155.010200
NAME OF SUBMITTER:	Shoba Jaglal
Signature:	/sjaglal/
Date:	08/13/2013

Total Attachments: 31
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COLLATERAL ASSIGNMENT OF PATENT AGREEMENT

THIS COLLATERAL ASSIGNMENT OF PATENT AGREEMENT ("Assignment"), dated as of September 1, 2011, made by and between **MOLECULAR IMPRINTS, INC.**, a Delaware corporation ("Assignor"), and **CANON INC.**, a Japanese corporation ("Assignee").

WHEREAS, Assignor and Assignee are parties to that certain Term Loan Agreement dated as of August 9, 2011 (as same may be amended, modified, supplemented and/or restated from time to time, the "Loan Agreement"); and Assignor and Assignee are parties to that certain Collateral Agreement, dated as of August 9, 2011 (as same may be amended, modified, supplemented and/or restated from time to time, the "Collateral Agreement"). Capitalized terms used but not defined herein shall have the meanings given to them in the Loan Agreement.

WHEREAS, pursuant to the Loan Agreement, Assignee has agreed to make a loan to Assignor upon the terms and subject to the conditions set forth in the Loan Agreement; and pursuant to the Collateral Agreement, Assignee has granted a security interest in certain of its assets, including all patents and patent applications, to secure the Obligations.

WHEREAS, it is a condition to the obligation of the Assignee to make the loan to Assignor under the Loan Agreement, that Assignor shall have executed and delivered this Assignment.

NOW, THEREFORE, in order to induce Assignee to make the loan, for one dollar in hand paid to Assignor, and other good and valuable consideration, the receipt and sufficiency of which is hereby acknowledged by Assignor, Assignor and Assignee hereby agree as follows:

1. As collateral security for the prompt and complete payment and performance when due (whether at the stated maturity, by acceleration or otherwise) of the Obligations (as defined in the Loan Agreement), Assignor does hereby grant and assign to Assignee all of its right, title and interest in and to the United States patents and patent applications listed on the annexed Schedule A, all inventions covered thereby, all re-issue, division, continuation, continuation-in-part, renewal and extension patents and all rights corresponding thereto throughout the world, including all of Assignor's rights under the International Convention (hereinafter individually or collectively, "Patents"), and all of Assignor's right, title and interest in any causes of action or rights of recovery that Assignor may have for any past infringement of the Patents. Assignor acknowledges and represents that Schedule A annexed hereto lists all of the United States patents and patent applications that are owned or controlled by Assignor or its Affiliates.

2. Until written notice of revocation by Assignee to Assignor after the occurrence and during the existence of an Event of Default, Assignee hereby grants to Assignor the exclusive right and license (to the exclusion of any right of the Assignee):

   a. To make, have made, use and sell throughout the world the inventions covered by the Patents;

b. To prosecute, maintain, defend and enforce, and to commence and control the prosecution and defense of any action or proceeding relating to, the Patents in the United States Patent and Trademark Office or before any foreign patent office or before any Court or other judicial or quasi-judicial body, solely in Assignor's own name;

c. To settle or compromise any action or proceeding brought or commenced in the United States Patent and Trademark Office or in any foreign patent office, or before any Court or other judicial or quasi-judicial body, involving or relating to any Patents, without the prior consent or approval of Assignee, including without limitation any action involving the infringement, validity or enforceability of the Patents, or any interference or other Patent and Trademark Office proceedings or other Patent and Trademark Office proceedings relating to the Patents;

d. To recover for all past, present and future infringements of the Patents, including without limitation all damages, costs and attorneys' fees relating thereto;

e. To receive all license royalties or other consideration related to the Patents;

f. To have any applications for Patents that are pending as of the effective date of this Assignment issue solely in the name of Assignor (and not, for the avoidance of doubt, issue in the name of Assignee notwithstanding the assignment set forth in Section 1 hereof); and

g. To maintain, including without limitation the payment of all maintenance, annuity or renewal fees, all Patent rights unless Assignor shall have received prior written consent of Assignee's abandonment.

3. Upon request by Assignor, Assignee agrees to execute such documents and to cooperate with Assignor as may reasonably be necessary in connection with the prosecution, maintenance, defense and enforcement of the Patents and to effect the licenses granted to Assignor by Section 2.

4. Until written notice of revocation by Assignee after the occurrence and during the existence of an Event of Default, Assignee hereby grants to Assignor a Power of Attorney with full power of substitution and revocation, including a power to appoint attorneys and associate attorneys, and to revoke their powers, to file, and assent to the filing of, prosecute, amend, alter and receive Letters Patent in Assignor's own name (including without limitation reissue patents), and to transact any and all business in the United States Patent and Trademark Office or before any foreign patent office or before any other judicial or quasi-judicial body, relating to the Patents.

5. Upon the occurrence and during the existence of an Event of Default, Assignor's exclusive rights and licenses granted under Section 2 hereof shall be subject to Assignee's rights and remedies under the Collateral Agreement and other applicable agreements and those rights and remedies granted to a secured party under the Uniform Commercial Code, as enacted in any jurisdiction in which the Patents may be located.

6. Assignor warrants that it holds unencumbered title to the Patents, subject to this Assignment. Assignor agrees not to sell, assign or encumber its interest in, or grant any license with respect to, the Patents without the prior written consent of Assignee, except as permitted under the Loan Agreement. Any attempted sale, assignment or encumbrance not made by Assignor in accordance with this Section 6 shall be void.

7. If Assignor should obtain rights to, or become entitled to the benefit of, any reissue, division, continuation, continuation-in-part, renewal or extension patents or patent applications for the Patents, Assignor shall give Assignee prompt written notice thereof to Assignee or as otherwise contemplated by the Collateral Agreement and the provisions of this Assignment shall automatically apply thereto.

8. Nothing herein shall be construed or deemed to grant to Assignee any express or implied right, title or interest in or to any patent or patent application of Assignor other than the Patents as expressly enumerated herein, other than as necessary to practice the inventions patented by the Patents.

9. Prior to the occurrence of an Event of Default, Assignee covenants and agrees that it shall not (a) sell, assign, transfer or convey to any third party, or otherwise encumber, any right, title or interest it may have in the Patents, or (b) otherwise interfere with any of Assignor's exclusive rights and licenses granted hereunder.

10. At such time as the Obligations (other than any indemnification or similar obligation that survives the termination of the Loan Agreement or the Collateral Agreement and as to which no claim is then pending) shall have been indefeasibly paid in full, all right, title and interest granted by Assignor to Assignee herein shall immediately and automatically revert and transfer back to Assignor. Assignee agrees to cooperate with Assignor and to execute such documents upon request as may reasonably be necessary to formalize and record such reversion and transfer back.

11. This Assignment shall inure to the benefit of and be binding upon the respective successors and permitted assigns of the parties.

IN WITNESS WHEREOF, Assignor and Assignee have executed this instrument.

MOLECULAR IMPRINTS, INC.

By:____________________
Name: DAVID S. GINO
Title: COO/CFO

CANON INC.

By:____________________
Name:____________________
Title:____________________

IN WITNESS WHEREOF, Assignor and Assignee have executed this instrument.

MOLECULAR IMPRINTS, INC.	**CANON INC.**
By:____________________	By: Tsuneji Uchida
Name:____________________	Name: Tsuneji Uchida
Title:____________________	Title: President & COO

SCHEDULE A

PATENT NO.	ISSUE DATE	TITLE	INVENTORS
7,136,150	14-Nov-2006	Imprint Lithography Template Having Opaque Alignment Marks	Sreenivasan, Sidlgata V.; Schumaker, Philip D.
7,140,861	28-Nov-2006	Compliant Hard Template for UV Imprinting	Watts, Michael P.C.; Voisin, Ronald D.; Sreenivasan, Sidlgata V.
7,019,835	28-Mar-2006	Method and System to Measure Characteristics of a Film Disposed on a Substrate	McMackin, Ian Matthew; Schumaker, Philip D.; Choi, Byung-Jin; Sreenivasan, Sidlgata V.; Watts, Michael P.C.
7,785,526	31-Aug-2010	Imprint Alignment Method, System and Template	Voisin, Ronald D.
7,122,079	17-Oct-2006	Composition for an Etching Mask Comprising a Silicon-Containing Material	Xu, Frank Y.; Miller, Michael N.; Watts, Michael P.C.
7,323,130	29-Jan-2008	Magnification Correction Employing Out-Of-Plane Distortion of a Substrate	Nimmakayala, Pawan Kumar; Sreenivasan, Sidlgata V.; Choi, Byung-Jin; Cherala, Anshuman
7,309,225	18-Dec-2007	Moat system for an imprint lithography template	McMackin, Ian Matthew; Lad, Pankaj B.
7,105,452	12-Sep-2006	Method Of Planarizing A Semiconductor Substrate with an Etching Chemistry (as amended)	Sreenivasan, Sidlgata V.
7,252,715	07-Aug-2007	System for Dispensing Liquids	Watts, Michael P.C.; Choi, Byung-Jin; Sreenivasan, Sidlgata V.
7,036,389	02-May-2006	System for Determining Characteristics of Substrates Employing Fluid Geometries	Choi, Byung-Jin; Sreenivasan, Sidlgata V.
6,982,783	03-Jan-2006	Chucking System for Modulating Shapes of Substrates	Choi, Byung-Jin; Voisin, Ronald D.; Sreenivasan, Sidlgata V.; Watts, Michael P.C.; Babbs, Daniel A.; Meissl, Mario Johannes; Bailey, Hillman L.; Schumaker, Norman E.
7,244,386	17-Jul-2007	Method of Compensating for a Volumetric Shrinkage of a Material Disposed upon a Substrate to Form a Substantially Planar Structure Therefrom	Sreenivasan, Sidlgata V.; Xu, Frank Y.
7,252,777	07-Aug-2007	Method of Forming an In-situ Recessed Structure	Vidusek, David; Sreenivasan, Sidlgata V.; Wang, David C.
7,041,604	09-May-2006	Method of Patterning Surfaces While Providing Greater Control of Recess Anisotropy (as amended)	Miller, Michael N.; Stacey, Nicholas A.
7,256,131	14-Aug-2007	Method of Controlling the Critical Dimension of Structures Formed on a Substrate	LaBrake, Dwayne L.
7,282,550	16-Oct-2007	Composition To Provide A Layer With Uniform Etch Characteristics	Xu, Frank Y.; Stacey, Nicholas A.

PATENT NO.	ISSUE DATE	TITLE	INVENTORS
7,939,131	10-May-2011	Method To Provide A Layer With Uniform Etch Characteristics	Xu, Frank Y.; Mackay, Christopher J.; Lad, Pankaj B.; McMackin, Ian Matthew; Truskett, Van Nguyen; Martin, Wesley; Fletcher, Edward B.; Wang, David C.; Stacey, Nicholas A.; Watts, Michael P.C.
6,990,870	31-Jan-2006	System for Determining Characteristics of Substrates Employing Fluid Geometries	Choi, Byung-Jin; Sreenivasan, Sidlgata V.
7,241,395	10-Jul-2007	Reverse Tone Patterning on Surfaces Having Surface Planarity Perturbations	Sreenivasan, Sidlgata V.; Stacey, Nicholas A.
7,547,504	16-Jun-2009	Pattern Reversal Employing Thick Residual Layers	Sreenivasan, Sidlgata V.
7,186,656	06-Mar-2007	Method of Forming a Recessed Structure Employing a Reverse Tone Process	Sreenivasan, Sidlgata V.
7,205,244	17-Apr-2007	Patterning Substrates Employing Multi-Film Layers Defining Etch Differential Interfaces	Stacey, Nicholas A.; Sreenivasan, Sidlgata V.; Miller, Michael N.
7,635,445	22-Dec-2009	Methods of Separating a Mold from a Solidified Layer Disposed on a Substrate	Choi, Byung-Jin; Cherala, Anshuman; Choi, Yeong-jun; Meissl, Mario Johannes; Sreenivasan, Sidlgata V.; Schumaker, Norman E.; Lu, Xiaoming; McMackin, Ian Matthew; Babbs, Daniel A.
7,292,326	06-Nov-2007	Interferometric Analysis for the Manufacture of Nano-Scale Devices	Nimmakayala, Pawan Kumar; Rafferty, Tom H.; Aghili, Alireza; Choi, Byung-Jin; Schumaker, Philip D.; Babbs, Daniel A.
7,630,067	08-Dec-2009	Interferometric Analysis Method for the Manufacture of Nano-Scale Devices	Nimmakayala, Pawan Kumar; Rafferty, Tom H.; Aghili, Alireza; Choi, Byung-Jin; Schumaker, Philip D.; Babbs, Daniel A.; Truskett, Van Nguyen
7,798,801	21-Sep-2010	Chucking System for Nano-Manufacturing	Babbs, Daniel A.; Choi, Byung-Jin; Cherala, Anshuman
7,636,999	29-Dec-2009	Method of Retaining a Substrate to a Wafer Chuck	Choi, Byung-Jin; Cherala, Anshuman; Babbs, Daniel A.
7,170,589	30-Jan-2007	Apparatus to Vary Dimensions of a Substrate During Nano-Scale Manufacturing	Cherala, Anshuman; Choi, Byung-Jin; Nimmakayala, Pawan Kumar; Meissl, Mario Johannes; Sreenivasan, Sidlgata V.
7,811,505	12-Oct-2010	Method For Fast Filling Of Templates For Imprint Lithography Using On Template Dispense	McMackin, Ian Matthew; Lad, Pankaj B.; Truskett, Van Nguyen
7,281,919	16-Oct-2007	System for Controlling a Volume of Material on a Mold	Shackleton, Steven C; McMackin, Ian Matthew; Lad, Pankaj B.; Truskett, Van Nguyen
7,307,118	11-Dec-2007	Composition to Reduce Adhesion between a Conformable Region and a Mold	Xu, Frank Y.; Miller, Michael N.
7,298,456	20-Nov-2007	System for Varying Dimensions of a Substrate During Nanoscale Manufacturing	Cherala, Anshuman; Choi, Byung-Jin; Nimmakayala, Pawan Kumar; Meissl, Mario Johannes; Sreenivasan, Sidlgata V.

PATENT NO.	ISSUE DATE	TITLE	INVENTORS
7,338,275	04-Mar-2008	Formation of Discontinuous Films During an Imprint Lithography Process	Choi, Byung-Jin; Sreenivasan, Sidlgata V.; Meissl, Mario Johannes; Watts, Michael P.C.
7,727,453	01-Jun-2010	Step and Repeat Imprint Lithography Processes	Sreenivasan, Sidlgata V.; Choi, Byung-Jin; Schumaker, Norman E.; Voisin, Ronald D.; Watts, Michael P.C.; Meissl, Mario Johannes
7,420,654	02-Sep-2008	Method of Varying Dimensions of a Substrate During Nano-Scale Manufacturing	Cherala, Anshuman; Choi, Byung-Jin; Nimmakayala, Pawan Kumar; Meissl, Mario Johannes; Sreenivasan, Sidlgata V.
7,316,554	08-Jan-2008	System to Control an Atmosphere between a Body and a Substrate	Choi, Yeong-jun; Choi, Byung-Jin
7,665,981	23-Feb-2010	System to Transfer a Template Transfer Body between a Motion Stage and a Docking Plate	Schumaker, Philip D.; Fancello, Angelo; Kim, Jae H.; Choi, Byung-Jin; Babbs, Daniel A.
7,387,508	17-Jun-2008	Compliant Device for Nano-Scale Manufacturing	Choi, Byung-Jin; Sreenivasan, Sidlgata V.
7,803,308	28-Sep-2010	Technique for Separating a Mold from Solidified Imprinting Material	GanapathiSubramanian, Mahadevan; Choi, Byung-Jin; Miller, Michael N.; Stacey, Nicholas A.
7,259,102	21-Aug-2007	Etching Technique to Planarize a Multi-Layer Structure	Wang, David C.; Xu, Frank Y.
7,759,407	20-Jul-2010	Composition for Adhering Materials Together	Xu, Frank Y.
7,670,534	02-Mar-2010	Method to Control an Atmosphere Between a Body and a Substrate	Choi, Yeong-jun; Choi, Byung-Jin
7,837,921	23-Nov-2010	Method of Providing Desirable Wetting and Release Characteristics Between a Mold and a Polymerizable Composition	Xu, Frank Y.; Lad, Pankaj B.; McMackin, Ian Matthew; Truskett, Van Nguyen; Fletcher, Edward B.
7,279,113	09-Oct-2007	A Method of Forming a Compliant Template for UV Imprinting	Watts, Michael P.C.; Voisin, Ronald D.; Sreenivasan, Sidlgata V.
7,357,876	15-Apr-2008	Eliminating Printability of Sub-Resolution Defects in Imprint Lithography	Sreenivasan, Sidlgata V.
7,906,058	15-Mar-2011	Bifurcated Contact Printing Technique	GanapathiSubramanian, Mahadevan; Choi, Byung-Jin; Miller, Michael N.; Stacey, Nicholas A.; Watts, Michael P.C.
7,224,443	29-May-2007	Imprint Lithography Substrate Processing Tool for Modulating Shapes of Substrates	Choi, Byung-Jin; Voisin, Ronald D.; Sreenivasan, Sidlgata V.; Watts, Michael P.C.; Babbs, Daniel A.; Meissl, Mario Johannes; Bailey, Hillman L.; Schumaker, Norman E.
7,037,639	02-May-2006	Methods of Manufacturing a Lithography Template	Voisin, Ronald D.
7,261,831	28-Aug-2007	Positive Tone Bi-Layer Imprint Lithography Method	Sreenivasan, Sidlgata V.
7,906,180	15-Mar-2011	Composition for an Etching Mask Comprising a Silicon-Containing Material	Xu, Frank Y.; Miller, Michael N.; Watts, Michael P.C.

PATENT NO.	ISSUE DATE	TITLE	INVENTORS
7,491,637	17-Feb-2009	Formation of Conductive Templates Employing Indium Tin Oxide	Sreenivasan, Sidlgata V.; McMackin, Ian Matthew; Choi, Byung-Jin; Voisin, Ronald D.
7,691,313	06-Apr-2010	Method for Expelling Gas Positioned Between a Substrate and a Mold	Choi, Byung-Jin; Sreenivasan, Sidlgata V.; McMackin, Ian Matthew; Lad, Pankaj B.
7,670,529	02-Mar-2010	Method and System for Double-Sided Patterning of Substrates	Choi, Byung-Jin; Sreenivasan, Sidlgata V.
7,670,530	02-Mar-2010	Patterning Substrates Employing Multiple Chucks	Choi, Byung-Jin; Sreenivasan, Sidlgata V.
7,323,417	29-Jan-2008	Method of Forming a Recessed Structure Employing a Reverse Tone Process	Sreenivasan, Sidlgata V.
7,635,263	22-Dec-2009	Chucking System Comprising an Array of Fluid Chambers	Cherala, Anshuman; Choi, Byung-Jin; Lad, Pankaj B.; Shackleton, Steven C
7,699,598	20-Apr-2010	Conforming Template for Patterning Liquids Disposed on Substrates	Sreenivasan, Sidlgata V.; Choi, Byung-Jin; Voisin, Ronald D.
7,780,893	24-Aug-2010	Method of concurrently patterning a substrate having a plurality of fields and a plurality of alignment marks	Sreenivasan, Sidlgata V.; McMackin, Ian Matthew; Melliar-Smith, Christopher M.; Choi, Byung-Jin
7,547,398	16-Jun-2009	Self-Aligned Process for Fabricating Imprint Templates Containing Variously Etched Features	Schmid, Gerard M.; Stacey, Nicholas A.; Resnick, Douglas J.; Voisin, Ronald D.; Myron, Lawrence J.
7,462,028	09-Dec-2008	Partial Vacuum Environment Imprinting	Cherala, Anshuman; Lad, Pankaj B.; McMackin, Ian Matthew; Choi, Byung-Jin
7,802,978	28-Sep-2010	Imprinting of Partial Fields at the Edge of the Wafer	Sreenivasan, Sidlgata V.; Choi, Byung-Jin
7,854,867	21-Dec-2010	Method for Detecting a Particle in a Nanoimprint Lithography System	Schumaker, Philip D.
7,641,840	05-Jan-2010	METHOD FOR EXPELLING GAS POSITIONED BETWEEN A SUBSTRATE AND A MOLD	Choi, Byung-Jin; GanapathiSubramanian, Mahadevan; Choi, Yeong-jun; Meissl, Mario Johannes
7,473,090	06-Jan-2009	Imprint Lithography Template to Facilitate Control of Liquid Movement	McMackin, Ian Matthew; Lad, Pankaj B.; Truskett, Van Nguyen
6,926,929	09-Aug-2005	System and Method For Dispensing Liquids	Watts, Michael P.C.; Choi, Byung-Jin; Sreenivasan, Sidlgata V.
7,670,953	02-Mar-2010	Positive Tone Bi-Layer Method	Sreenivasan, Sidlgata V.
7,906,274	15-Mar-2011	Method of Creating a Template Employing a Lift-Off Process	Schmid, Gerard M.; Resnick, Douglas J.; Miller, Michael N.
7,837,907	23-Nov-2010	Alignment System and Method for a Substrate in a Nano-Imprint Process	Nimmakayala, Pawan Kumar; Choi, Byung-Jin
6,932,934	23-Aug-2005	Formation of Discontinuous Films During an Imprint Lithography Process	Choi, Byung-Jin; Meissl, Mario Johannes; Sreenivasan, Sidlgata V.; Watts, Michael P.C.
7,845,931	07-Dec-2010	Polymerization Technique to	Xu, Frank Y.; Fletcher, Edward B.; Lad, Pankaj

PATENT NO.	ISSUE DATE	TITLE	INVENTORS
		Attenuate Oxygen Inhibition of Solidification of Liquids and Composition Therefor	B.; Watts, Michael P.C.
7,077,992	18-Jul-2006	Step and Repeat Imprint Lithography Process	Sreenivasan, Sidlgata V.; Choi, Byung-Jin; Schumaker, Norman E.; Voisin, Ronald D.; Watts, Michael P.C.; Meissl, Mario Johannes
6,900,881	31-May-2005	Step and Repeat Imprint Lithography Systems	Sreenivasan, Sidlgata V.; Watts, Michael P.C.; Choi, Byung-Jin; Meissl, Mario Johannes; Schumaker, Norman E.; Voisin, Ronald D.
7,708,926	04-May-2010	Capillary Imprinting Technique	Choi, Byung-Jin; Sreenivasan, Sidlgata V.
7,795,132	14-Sep-2010	Self-Aligned Cross-Point Memory Fabrication	Sreenivasan, Sidlgata V.; Melliar-Smith, Christopher M.; LaBrake, Dwayne L.
6,908,861	21-Jun-2005	Method for Imprint Lithography Using an Electric Field	Sreenivasan, Sidlgata V.; Bonnecaze, Roger T.; Willson, Carlton Grant
7,071,088	04-Jul-2006	Method for Fabricating Bulbous-Shaped Vias	Watts, Michael P.C.; Sreenivasan, Sidlgata V.
7,027,156	11-Apr-2006	Scatterometry Alignment for Imprint Lithography	Watts, Michael P.C.; McMackin, Ian Matthew
7,070,405	04-Jul-2006	Alignment Systems for Imprint Lithography	Sreenivasan, Sidlgata V.; Watts, Michael P.C.; Choi, Byung-Jin; Voisin, Ronald D.; Schumaker, Norman E.
6,916,584	12-Jul-2005	Alignment Methods for Imprint Lithography	Sreenivasan, Sidlgata V.; Watts, Michael P.C.; Choi, Byung-Jin; Voisin, Ronald D.
6,936,194	30-Aug-2005	Functional Patterning Material For Imprint Lithography Processes	Watts, Michael P.C.
6,871,558	29-Mar-2005	Method for Determining Characteristics of Substrates Employing Fluid Geometries	Choi, Byung-Jin; Sreenivasan, Sidlgata V.
7,785,096	31-Aug-2010	Enhanced Multi Channel Alignment	Nimmakayala, Pawan Kumar; Choi, Byung-Jin; Rafferty, Tom H.; Schumaker, Philip D.
7,927,541	19-Apr-2011	Full-Wafer or Large Area Imprinting with Multiple Separated Sub-Fields for High Throughput Lithography	Sreenivasan, Sidlgata V.
6,929,762	16-Aug-2005	Method of Reducing Pattern Distortions During Imprint Lithography Processes	Rubin, Daniel I.
7,019,819	28-Mar-2006	Chucking System for Modulating Shapes of Substrates	Choi, Byung-Jin; Voisin, Ronald D.; Sreenivasan, Sidlgata V.; Watts, Michael P.C.; Babbs, Daniel A.; Meissl, Mario Johannes; Bailey, Hillman L.; Schumaker, Norman E.
7,880,872	01-Feb-2011	Interferometric Analysis Method for the Manufacture of Nano-Scale Devices	Nimmakayala, Pawan Kumar; Rafferty, Tom H.; Aghili, Alireza; Choi, Byung-Jin; Schumaker, Philip D.; Babbs, Daniel A.; Truskett, Van Nguyen
7,874,831	25-Jan-2011	Template Having a Silicon Nitride, Silicon Carbide or Silicon Oxynitride Film	Resnick, Douglas J.; Meissl, Mario Johannes; Selinidis, Kosta S.; Xu, Frank Y.
6,980,282	27-Dec-2005	Method for Modulating Shapes of Substrates	Choi, Byung-Jin; Voisin, Ronald D.; Sreenivasan, Sidlgata V.; Watts, Michael P.C.; Willson, Carlton Grant; Schumaker, Norman

PATENT NO.	ISSUE DATE	TITLE	INVENTORS
			E.; Meissl, Mario Johannes
7,931,846	26-Apr-2011	Method to Control an Atmosphere Between a Body and a Substrate	Choi, Yeong-jun; Choi, Byung-Jin
7,858,528	28-Dec-2010	Positive Tone Bi-Layer Method	Sreenivasan, Sidlgata V.
7,132,225	07-Nov-2006	Methods of Inspecting a Lithography Template	Voisin, Ronald D.
7,910,042	22-Mar-2011	Capillary Imprinting Technique	Choi, Byung-Jin; Sreenivasan, Sidlgata V.
7,943,081	17-May-2011	Step and Repeat Imprint Lithography Processes	Sreenivasan, Sidlgata V.; Choi, Byung-Jin; Schumaker, Norman E.; Voisin, Ronald D.; Watts, Michael P.C.; Meissl, Mario Johannes
7,452,574	18-Nov-2008	Method to Reduce Adhesion Between a Polymerizable Layer and a Substrate Employing a Fluorine-Containing Layer	Truskett, Van Nguyen; Mackay, Christopher J.; Choi, Byung-Jin
7,947,608	24-May-2011	Positive Tone Bi-Layer Method	Sreenivasan, Sidlgata V.
6,805,054	19-Oct-2004	Method, System and Holder for Transferring Templates During Imprint Lithography Processes	Meissl, Mario Johannes; Choi, Byung-Jin; Babbs, Daniel A.; Bailey, Hillman L.
7,179,396	20-Feb-2007	Positive Tone Bi-Layer Imprint Lithography Method	Sreenivasan, Sidlgata V.
7,396,475	08-Jul-2008	Method of Forming Stepped Structures Employing Imprint Lithography	Sreenivasan, Sidlgata V.
6,951,173	04-Oct-2005	Assembly and Method for Transferring Imprint Lithography Templates	Meissl, Mario Johannes; Choi, Byung-Jin
7,442,336	28-Oct-2008	Capillary Imprinting Technique	Choi, Byung-Jin; Sreenivasan, Sidlgata V.; Watts, Michael P.C.
7,179,079	20-Feb-2007	Conforming Template for Patterning Liquids Disposed on Substrates	Sreenivasan, Sidlgata V.; Choi, Byung-Jin; Voisin, Ronald D.
7,150,622	19-Dec-2006	Systems for Magnification and Distortion Correction for Imprint Lithography Processes	Choi, Byung-Jin; Sreenivasan, Sidlgata V.; Meissl, Mario Johannes
7,531,025	12-May-2009	Method for Creating A Turbulent Flow Of Fluid Between A Mold And A Substrate	McMackin, Ian Matthew; Stacey, Nicholas A.; Babbs, Daniel A.; Voth, Duane; Watts, Michael P.C.; Truskett, Van Nguyen; Xu, Frank Y.; Voisin, Ronald D.; Lad, Pankaj B.
7,270,533	18-Sep-2007	System for Creating a Turbulent Flow of Fluid Between a Mold and a Substrate	McMackin, Ian Matthew; Stacey, Nicholas A.; Babbs, Daniel A.; Voth, Duane; Watts, Michael P.C.; Truskett, Van Nguyen; Xu, Frank Y.; Voisin, Ronald D.; Lad, Pankaj B.
7,768,624	03-Aug-2010	METHOD FOR OBTAINING FORCE COMBINATIONS FOR TEMPLATE DEFORMATION USING NULLSPACE AND METHODS OPTIMIZATION TECHNIQUES	Cherala, Anshuman; Sreenivasan, Sidlgata V.; Choi, Byung-Jin; Thompson, Ecron D.
7,815,824	19-Oct-2010	REAL TIME IMPRINT PROCESS DIAGNOSTICS FOR DEFECTS	Sreenivasan, Sidlgata V.; Singhal, Shrawan; Choi, Byung-Jin

PATENT NO.	ISSUE DATE	TITLE	INVENTORS
7,261,830	28-Aug-2007	Applying Imprinting Material to Substrates Employing Electromagnetic Fields	Cherala, Anshuman; Sreenivasan, Sidlgata V.; Schumaker, Norman E.
7,090,716	15-Aug-2006	Single Phase Fluid Imprint Lithography Method	McMackin, Ian Matthew; Stacey, Nicholas A.; Babbs, Daniel A.; Voth, Duane; Watts, Michael P.C.; Truskett, Van Nguyen; Xu, Frank Y.; Voisin, Ronald D.; Lad, Pankaj B.
7,157,036	02-Jan-2007	Method to Reduce Adhesion Between a Conformable Region and a Pattern of a Mold	Choi, Byung-Jin; Xu, Frank Y.; Stacey, Nicholas A.; Truskett, Van Nguyen; Watts, Michael P.C.
7,122,482	17-Oct-2006	Methods for Fabricating Patterned Features Utilizing Imprint Lithography	Xu, Frank Y.; Stacey, Nicholas A.; Watts, Michael P.C.; Thompson, Ecron D.

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026842/0929 PAGE 2

APPLICATION NUMBER: 10670980 FILING DATE: 09/25/2003
PATENT NUMBER: 7136150 ISSUE DATE: 11/14/2006
TITLE: IMPRINT LITHOGRAPHY TEMPLATE HAVING OPAQUE ALIGNMENT MARKS

APPLICATION NUMBER: 10833240 FILING DATE: 04/27/2004
PATENT NUMBER: 7140861 ISSUE DATE: 11/28/2006
TITLE: COMPLIANT HARD TEMPLATE FOR UV IMPRINTING

APPLICATION NUMBER: 10782187 FILING DATE: 02/19/2004
PATENT NUMBER: 7019835 ISSUE DATE: 03/28/2006
TITLE: METHOD AND SYSTEM TO MEASURE CHARACTERISTICS OF A FILM DISPOSED ON A SUBSTRATE

APPLICATION NUMBER: 10895214 FILING DATE: 07/20/2004
PATENT NUMBER: 7785526 ISSUE DATE: 08/31/2010
TITLE: IMPRINT ALIGNMENT METHOD, SYSTEM, AND TEMPLATE

APPLICATION NUMBER: 10789319 FILING DATE: 02/27/2004
PATENT NUMBER: 7122079 ISSUE DATE: 10/17/2006
TITLE: COMPOSITION FOR AN ETCHING MASK COMPRISING A SILICON-CONTAINING MATERIAL

APPLICATION NUMBER: 10735110 FILING DATE: 12/12/2003
PATENT NUMBER: 7323130 ISSUE DATE: 01/29/2008
TITLE: MAGNIFICATION CORRECTION EMPLOYING OUT-OF-PLANE DISTORTION OF A SUBSTRATE

APPLICATION NUMBER: 10917761 FILING DATE: 08/13/2004
PATENT NUMBER: 7309225 ISSUE DATE: 12/18/2007
TITLE: MOAT SYSTEM FOR AN IMPRINT LITHOGRAPHY TEMPLATE

APPLICATION NUMBER: 10917563 FILING DATE: 08/13/2004
PATENT NUMBER: 7105452 ISSUE DATE: 09/12/2006
TITLE: METHOD OF PLANARIZING A SEMICONDUCTOR SUBSTRATE WITH AN ETCHING CHEMISTRY

APPLICATION NUMBER: 10868683 FILING DATE: 06/15/2004
PATENT NUMBER: 7252715 ISSUE DATE: 08/07/2007
TITLE: SYSTEM FOR DISPENSING LIQUIDS

APPLICATION NUMBER: 10863800 FILING DATE: 06/08/2004
PATENT NUMBER: 7036389 ISSUE DATE: 05/02/2006
TITLE: SYSTEM FOR DETERMINING CHARACTERISTICS OF SUBSTRATES EMPLOYING FLUID GEOMETRIES

026842/0929 PAGE 3

APPLICATION NUMBER: 10864591 FILING DATE: 06/09/2004
PATENT NUMBER: 6982783 ISSUE DATE: 01/03/2006
TITLE: CHUCKING SYSTEM FOR MODULATING SHAPES OF SUBSTRATES

APPLICATION NUMBER: 10951014 FILING DATE: 09/27/2004
PATENT NUMBER: 7244386 ISSUE DATE: 07/17/2007
TITLE: METHOD OF COMPENSATING FOR A VOLUMETRIC SHRINKAGE OF A MATERIAL DISPOSED UPON A SUBSTRATE TO FORM A SUBSTANTIALLY PLANAR STRUCTURE THEREFROM

APPLICATION NUMBER: 10946565 FILING DATE: 09/21/2004
PATENT NUMBER: 7252777 ISSUE DATE: 08/07/2007
TITLE: METHOD OF FORMING AN IN-SITU RECESSED STRUCTURE

APPLICATION NUMBER: 10946159 FILING DATE: 09/21/2004
PATENT NUMBER: 7041604 ISSUE DATE: 05/09/2006
TITLE: METHOD OF PATTERNING SURFACES WHILE PROVIDING GREATER CONTROL OF RECESS ANISOTROPY

APPLICATION NUMBER: 11184664 FILING DATE: 07/19/2005
PATENT NUMBER: 7256131 ISSUE DATE: 08/14/2007
TITLE: METHOD OF CONTROLLING THE CRITICAL DIMENSION OF STRUCTURES FORMED ON A SUBSTRATE

APPLICATION NUMBER: 10919062 FILING DATE: 08/16/2004
PATENT NUMBER: 7282550 ISSUE DATE: 10/16/2007
TITLE: COMPOSITION TO PROVIDE A LAYER WITH UNIFORM ETCH CHARACTERISTICS

APPLICATION NUMBER: 10919224 FILING DATE: 08/16/2004
PATENT NUMBER: 7939131 ISSUE DATE: 05/10/2011
TITLE: METHOD TO PROVIDE A LAYER WITH UNIFORM ETCH CHARACTERISTICS

APPLICATION NUMBER: 10923628 FILING DATE: 08/20/2004
PATENT NUMBER: 6990870 ISSUE DATE: 01/31/2006
TITLE: SYSTEM FOR DETERMINING CHARACTERISTICS OF SUBSTRATES EMPLOYING FLUID GEOMETRIES

APPLICATION NUMBER: 10946577 FILING DATE: 09/21/2004
PATENT NUMBER: 7241395 ISSUE DATE: 07/10/2007
TITLE: REVERSE TONE PATTERNING ON SURFACES HAVING SURFACE PLANARITY PERTURBATIONS

APPLICATION NUMBER: 10946566 FILING DATE: 09/21/2004
PATENT NUMBER: 7547504 ISSUE DATE: 06/16/2009
TITLE: PATTERN REVERSAL EMPLOYING THICK RESIDUAL LAYERS

APPLICATION NUMBER: 10946570 FILING DATE: 09/21/2004
PATENT NUMBER: 7186656 ISSUE DATE: 03/06/2007
TITLE: METHOD OF FORMING A RECESSED STRUCTURE EMPLOYING A REVERSE TONE PROCESS

APPLICATION NUMBER: 10946574 FILING DATE: 09/21/2004
PATENT NUMBER: 7205244 ISSUE DATE: 04/17/2007
TITLE: PATTERNING SUBSTRATES EMPLOYING MULTI-FILM LAYERS DEFINING ETCH-DIFFERENTIAL INTERFACES

APPLICATION NUMBER: 11108208 FILING DATE: 04/18/2005
PATENT NUMBER: 7635445 ISSUE DATE: 12/22/2009
TITLE: METHOD OF SEPARATING A MOLD FROM A SOLIDIFIED LAYER DISPOSED ON A SUBSTRATE

APPLICATION NUMBER: 11000331 FILING DATE: 11/30/2004
PATENT NUMBER: 7292326 ISSUE DATE: 11/06/2007
TITLE: INTERFEROMETRIC ANALYSIS FOR THE MANUFACTURE OF NANO-SCALE DEVICES

APPLICATION NUMBER: 11000321 FILING DATE: 11/30/2004
PATENT NUMBER: 7630067 ISSUE DATE: 12/08/2009
TITLE: INTERFEROMETRIC ANALYSIS METHOD FOR THE MANUFACTURE OF NANO-SCALE DEVICES

APPLICATION NUMBER: 11047428 FILING DATE: 01/31/2005
PATENT NUMBER: 7798801 ISSUE DATE: 09/21/2010
TITLE: CHUCKING SYSTEM FOR NANO-MANUFACTURING

APPLICATION NUMBER: 11047499 FILING DATE: 01/31/2005
PATENT NUMBER: 7636999 ISSUE DATE: 12/29/2009
TITLE: METHOD OF RETAINING A SUBSTRATE TO A WAFER CHUCK

APPLICATION NUMBER: 11142839 FILING DATE: 06/01/2005
PATENT NUMBER: 7170589 ISSUE DATE: 01/30/2007
TITLE: APPARATUS TO VARY DIMENSIONS OF A SUBSTRATE DURING NANO-SCALE MANUFACTURING

APPLICATION NUMBER: 11101140 FILING DATE: 04/07/2005
PATENT NUMBER: 7811505 ISSUE DATE: 10/12/2010
TITLE: METHOD FOR FAST FILLING OF TEMPLATES FOR IMPRINT LITHOGRAPHY USING ON TEMPLATE DISPENSE

APPLICATION NUMBER: 11101139 FILING DATE: 04/07/2005
PATENT NUMBER: 7281919 ISSUE DATE: 10/16/2007
TITLE: SYSTEM FOR CONTROLLING A VOLUME OF MATERIAL ON A MOLD

APPLICATION NUMBER: 11068171 FILING DATE: 02/28/2005
PATENT NUMBER: 7307118 ISSUE DATE: 12/11/2007
TITLE: COMPOSITION TO REDUCE ADHESION BETWEEN A CONFORMABLE REGION AND A MOLD

APPLICATION NUMBER: 11142808 FILING DATE: 06/01/2005
PATENT NUMBER: 7298456 ISSUE DATE: 11/20/2007
TITLE: SYSTEM FOR VARYING DIMENSIONS OF A SUBSTRATE DURING NANOSCALE MANUFACTURING

APPLICATION NUMBER: 11126946 FILING DATE: 05/11/2005
PATENT NUMBER: 7338275 ISSUE DATE: 03/04/2008
TITLE: FORMATION OF DISCONTINUOUS FILMS DURING AN IMPRINT LITHOGRAPHY PROCESS

APPLICATION NUMBER: 11127041 FILING DATE: 05/11/2005
PATENT NUMBER: 7727453 ISSUE DATE: 06/01/2010
TITLE: STEP AND REPEAT IMPRINT LITHOGRAPHY PROCESSES

APPLICATION NUMBER: 11142834 FILING DATE: 06/01/2005
PATENT NUMBER: 7420654 ISSUE DATE: 09/02/2008
TITLE: METHOD OF VARYING DIMENSIONS OF A SUBSTRATE DURING NANO-SCALE MANUFACTURING

APPLICATION NUMBER: 11231616 FILING DATE: 09/21/2005
PATENT NUMBER: 7316554 ISSUE DATE: 01/08/2008
TITLE: SYSTEM TO CONTROL AN ATMOSPHERE BETWEEN A BODY AND A SUBSTRATE

APPLICATION NUMBER: 11211766 FILING DATE: 08/25/2005
PATENT NUMBER: 7665981 ISSUE DATE: 02/23/2010
TITLE: SYSTEM TO TRANSFER A TEMPLATE TRANSFER BODY BETWEEN A MOTION STAGE AND A DOCKING PLATE

APPLICATION NUMBER: 11142838 FILING DATE: 06/01/2005
PATENT NUMBER: 7387508 ISSUE DATE: 06/17/2008
TITLE: COMPLIANT DEVICE FOR NANO-SCALE MANUFACTURING

APPLICATION NUMBER: 11292568 FILING DATE: 12/01/2005
PATENT NUMBER: 7803308 ISSUE DATE: 09/28/2010
TITLE: TECHNIQUE FOR SEPARATING A MOLD FROM SOLIDIFIED IMPRINTING MATERIAL

APPLICATION NUMBER: 11240708 FILING DATE: 09/30/2005
PATENT NUMBER: 7259102 ISSUE DATE: 08/21/2007
TITLE: ETCHING TECHNIQUE TO PLANARIZE A MULTI-LAYER STRUCTURE

APPLICATION NUMBER: 11187406 FILING DATE: 07/22/2005
PATENT NUMBER: 7759407 ISSUE DATE: 07/20/2010
TITLE: COMPOSITION FOR ADHERING MATERIALS TOGETHER

APPLICATION NUMBER: 11231580 FILING DATE: 09/21/2005
PATENT NUMBER: 7670534 ISSUE DATE: 03/02/2010
TITLE: METHOD TO CONTROL AN ATMOSTPHERE BETWEEN A BODY AND A SUBSTRATE

APPLICATION NUMBER: 11244428 FILING DATE: 10/05/2005
PATENT NUMBER: 7837921 ISSUE DATE: 11/23/2010
TITLE: METHOD OF PROVIDING DESIRABLE WETTING AND RELEASE CHARACTERSTICS BETWEEN A MOLD AND A POLYMERIZABLE COMPOSITION

APPLICATION NUMBER: 11298244 FILING DATE: 12/09/2005
PATENT NUMBER: 7279113 ISSUE DATE: 10/09/2007
TITLE: METHOD OF FORMING A COMPLIANT TEMPLATE FOR UV IMPRINTING

APPLICATION NUMBER: 11292394 FILING DATE: 11/30/2005
PATENT NUMBER: 7357876 ISSUE DATE: 04/15/2008
TITLE: ELIMINATING PRINTABILITY OF SUB-RESOLUTION DEFECTS IN IMPRINT LITHOGRAPHY

APPLICATION NUMBER: 11303777 FILING DATE: 12/16/2005
PATENT NUMBER: 7906058 ISSUE DATE: 03/15/2011
TITLE: BIFURCATED CONTACT PRINTING TECHNIQUE

APPLICATION NUMBER: 11389731 FILING DATE: 03/27/2006
PATENT NUMBER: 7224443 ISSUE DATE: 05/29/2007
TITLE: IMPRINT LITHOGRAPHY SUBSTRATE PROCESSING TOOL FOR MODULATING SHAPES OF SUBSTRATES

APPLICATION NUMBER: 10136188 FILING DATE: 05/01/2002
PATENT NUMBER: 7037639 ISSUE DATE: 05/02/2006
TITLE: METHODS OF MANUFACTURING A LITHOGRAPHY TEMPLATE

APPLICATION NUMBER: 11560928 FILING DATE: 11/17/2006
PATENT NUMBER: 7261831 ISSUE DATE: 08/28/2007
TITLE: POSITIVE TONE BI-LAYER IMPRINT LITHOGRAPHY METHOD

APPLICATION NUMBER: 11508765 FILING DATE: 08/23/2006
PATENT NUMBER: 7906180 ISSUE DATE: 03/15/2011
TITLE: COMPOSITION FOR AN ETCHING MASK COMPRISING A SILICON-CONTAINING MATERIAL

APPLICATION NUMBER: 11470829 FILING DATE: 09/07/2006
PATENT NUMBER: 7491637 ISSUE DATE: 02/17/2009
TITLE: FORMATION OF CONDUCTIVE TEMPLATES EMPLOYING INDIUM TIN OXIDE

APPLICATION NUMBER: 11565393 FILING DATE: 11/30/2006
PATENT NUMBER: 7691313 ISSUE DATE: 04/06/2010
TITLE: METHOD FOR EXPELLING GAS POSITIONED BETWEEN A SUBSTRATE AND A MOLD

APPLICATION NUMBER: 11565350 FILING DATE: 11/30/2006
PATENT NUMBER: 7670529 ISSUE DATE: 03/02/2010
TITLE: METHOD AND SYSTEM FOR DOUBLE-SIDED PATTERNING OF SUBSTRATES

APPLICATION NUMBER: 11625082 FILING DATE: 01/19/2007
PATENT NUMBER: 7670530 ISSUE DATE: 03/02/2010
TITLE: PATTERNING SUBSTRATES EMPLOYING MULTIPLE CHUCKS

APPLICATION NUMBER: 11611287 FILING DATE: 12/15/2006
PATENT NUMBER: 7323417 ISSUE DATE: 01/29/2008
TITLE: METHOD OF FORMING A RECESSED STRUCTURE EMPLOYING A REVERSE TONE PROCESS

APPLICATION NUMBER: 11690480 FILING DATE: 03/23/2007
PATENT NUMBER: 7635263 ISSUE DATE: 12/22/2009
TITLE: CHUCKING SYSTEM COMPRISING AN ARRAY OF FLUID CHAMBERS

APPLICATION NUMBER: 11669569 FILING DATE: 01/31/2007
PATENT NUMBER: 7699598 ISSUE DATE: 04/20/2010
TITLE: CONFORMING TEMPLATE FOR PATTERNING LIQUIDS DISPOSED ON SUBSTRATES

APPLICATION NUMBER: 11695850 FILING DATE: 04/03/2007
PATENT NUMBER: 7780893 ISSUE DATE: 08/24/2010
TITLE: METHOD OF CONCURRENTLY PATTERNING A SUBSTRATE HAVING A PLURALITY OF FIELDS AND A PLURALITY OF ALIGNMENT MARKS

APPLICATION NUMBER: 11693236 FILING DATE: 03/29/2007
PATENT NUMBER: 7547398 ISSUE DATE: 06/16/2009
TITLE: SELF-ALIGNED PROCESS FOR FABRICATING IMPRINT TEMPLATES CONTAINING VARIOUSLY ETCHED FEATURES

APPLICATION NUMBER: 11695263 FILING DATE: 04/02/2007
PATENT NUMBER: 7462028 ISSUE DATE: 12/09/2008
TITLE: PARTIAL VACUUM ENVIRONMENT IMPRINTING

APPLICATION NUMBER: 11694500 FILING DATE: 03/30/2007
PATENT NUMBER: 7802978 ISSUE DATE: 09/28/2010
TITLE: IMPRINTING OF PARTIAL FIELDS AT THE EDGE OF THE WAFER

APPLICATION NUMBER: 11737301 FILING DATE: 04/19/2007
PATENT NUMBER: 7854867 ISSUE DATE: 12/21/2010
TITLE: METHOD FOR DETECTING A PARTICLE IN A NANOIMPRINT LITHOGRAPHY SYSTEM

APPLICATION NUMBER: 11749909 FILING DATE: 05/17/2007
PATENT NUMBER: 7641840 ISSUE DATE: 01/05/2010
TITLE: METHOD FOR EXPELLING GAS POSITIONED BETWEEN A SUBSTRATE AND A MOLD

APPLICATION NUMBER: 11762378 FILING DATE: 06/13/2007
PATENT NUMBER: 7473090 ISSUE DATE: 01/06/2009
TITLE: IMPRINT LITHOGRAPHY TEMPLATE TO FACILITATE CONTROL OF LIQUID MOVEMENT

APPLICATION NUMBER: 10191749 FILING DATE: 07/09/2002
PATENT NUMBER: 6926929 ISSUE DATE: 08/09/2005
TITLE: SYSTEM AND METHOD FOR DISPENSING LIQUIDS

APPLICATION NUMBER: 11844824 FILING DATE: 08/24/2007
PATENT NUMBER: 7670953 ISSUE DATE: 03/02/2010
TITLE: POSITIVE TONE BI-LAYER METHOD

APPLICATION NUMBER: 11943907 FILING DATE: 11/21/2007
PATENT NUMBER: 7906274 ISSUE DATE: 03/15/2011
TITLE: METHOD OF CREATING A TEMPLATE EMPLOYING A LIFT-OFF PROCESS

APPLICATION NUMBER: 12175258 FILING DATE: 07/17/2008
PATENT NUMBER: 7837907 ISSUE DATE: 11/23/2010
TITLE: ALIGNMENT SYSTEM AND METHOD FOR A SUBSTRATE IN A NANO-IMPRINT PROCESS

APPLICATION NUMBER: 10194411 FILING DATE: 07/11/2002
PATENT NUMBER: 6932934 ISSUE DATE: 08/23/2005
TITLE: FORMATION OF DISCONTINUOUS FILMS DURING AN IMPRINT LITHOGRAPHY PROCESS

APPLICATION NUMBER: 11858687 FILING DATE: 09/20/2007
PATENT NUMBER: 7845931 ISSUE DATE: 12/07/2010
TITLE: POLYMERIZATION TECHNIQUE TO ATTENUATE OXYGEN INHIBITION OF SOLIDIFICATION OF LIQUIDS AND COMPOSITION THEREFOR

APPLICATION NUMBER: 10194991 FILING DATE: 07/11/2002
PATENT NUMBER: 7077992 ISSUE DATE: 07/18/2006
TITLE: STEP AND REPEAT IMPRINT LITHOGRAPHY PROCESSES

APPLICATION NUMBER: 10194414 FILING DATE: 07/11/2002
PATENT NUMBER: 6900881 ISSUE DATE: 05/31/2005
TITLE: STEP AND REPEAT IMPRINT LITHOGRAPHY SYSTEMS

APPLICATION NUMBER: 12026049 FILING DATE: 02/05/2008
PATENT NUMBER: 7708926 ISSUE DATE: 05/04/2010
TITLE: CAPILLARY IMPRINTING TECHNIQUE

APPLICATION NUMBER: 12182905 FILING DATE: 07/30/2008
PATENT NUMBER: 7795132 ISSUE DATE: 09/14/2010
TITLE: SELF-ALIGNED CROSS-POINT MEMORY FABRICATION

APPLICATION NUMBER: 10194410 FILING DATE: 07/11/2002
PATENT NUMBER: 6908861 ISSUE DATE: 06/21/2005
TITLE: METHOD FOR IMPRINT LITHOGRAPHY USING AN ELECTRIC FIELD

APPLICATION NUMBER: 10227105 FILING DATE: 08/23/2002
PATENT NUMBER: 7071088 ISSUE DATE: 07/04/2006
TITLE: METHOD FOR FABRICATING BULBOUS-SHAPED VIAS

APPLICATION NUMBER: 10210785 FILING DATE: 08/01/2002
PATENT NUMBER: 7027156 ISSUE DATE: 04/11/2006
TITLE: SCATTEROMETRY ALIGNMENT FOR IMPRINT LITHOGRAPHY

APPLICATION NUMBER: 10210894 FILING DATE: 08/01/2002
PATENT NUMBER: 7070405 ISSUE DATE: 07/04/2006
TITLE: ALIGNMENT SYSTEMS FOR IMPRINT LITHOGRAPHY

APPLICATION NUMBER: 10210780 FILING DATE: 08/01/2002
PATENT NUMBER: 6916584 ISSUE DATE: 07/12/2005
TITLE: ALIGNMENT METHODS FOR IMPRINT LITHOGRAPHY

APPLICATION NUMBER: 10235314 FILING DATE: 09/05/2002
PATENT NUMBER: 6936194 ISSUE DATE: 08/30/2005
TITLE: FUNCTIONAL PATTERNING MATERIAL FOR IMPRINT LITHOGRAPHY PROCESSES

APPLICATION NUMBER: 10318365 FILING DATE: 12/12/2002
PATENT NUMBER: 6871558 ISSUE DATE: 03/29/2005
TITLE: METHOD FOR DETERMINING CHARACTERISTICS OF SUBSTRATE EMPLOYING FLUID GEOMETRIES

APPLICATION NUMBER: 12389673 FILING DATE: 02/20/2009
PATENT NUMBER: 7785096 ISSUE DATE: 08/31/2010
TITLE: ENHANCED MULTI CHANNEL ALIGNMENT

APPLICATION NUMBER: 12430428 FILING DATE: 04/27/2009
PATENT NUMBER: 7927541 ISSUE DATE: 04/19/2011
TITLE: FULL-WAFER OR LARGE AREA IMPRINTING WITH MULTIPLE SEPARATED SUB-FIELDS FOR HIGH THROUGHPUT LITHOGRAPHY

APPLICATION NUMBER: 10293223 FILING DATE: 11/13/2002
PATENT NUMBER: 6929762 ISSUE DATE: 08/16/2005
TITLE: METHOD OF REDUCING PATTERN DISTORTIONS DURING IMPRINT LITHOGRAPHY PROCESSES

APPLICATION NUMBER: 10293224 FILING DATE: 11/13/2002
PATENT NUMBER: 7019819 ISSUE DATE: 03/28/2006
TITLE: CHUCKING SYSTEM FOR MODULATING SHAPES OF SUBSTRATES

APPLICATION NUMBER: 12576030 FILING DATE: 10/08/2009
PATENT NUMBER: 7880872 ISSUE DATE: 02/01/2011
TITLE: INTERFEROMETRIC ANALYSIS METHOD FOR THE MANUFACTURE OF NANO-SCALE DEVICES

APPLICATION NUMBER: 12605848 FILING DATE: 10/26/2009
PATENT NUMBER: 7874831 ISSUE DATE: 01/25/2011
TITLE: TEMPLATE HAVING A SILICON NITRIDE, SILICON CARBIDE OR SILICON OXYNITRIDE FILM

026842/0929 PAGE 11

APPLICATION NUMBER: 10316963 FILING DATE: 12/11/2002
PATENT NUMBER: 6980282 ISSUE DATE: 12/27/2005
TITLE: METHOD FOR MODULATING SHAPES OF SUBSTRATES

APPLICATION NUMBER: 12688190 FILING DATE: 01/15/2010
PATENT NUMBER: 7931846 ISSUE DATE: 04/26/2011
TITLE: METHOD TO CONTROL AN ATMOSPHERE BETWEEN A BODY AND A SUBSTRATE

APPLICATION NUMBER: 12689773 FILING DATE: 01/19/2010
PATENT NUMBER: 7858528 ISSUE DATE: 12/28/2010
TITLE: POSITIVE TONE BI-LAYER METHOD

APPLICATION NUMBER: 10293919 FILING DATE: 11/13/2002
PATENT NUMBER: 7132225 ISSUE DATE: 11/07/2006
TITLE: METHODS OF INSPECTING A LITHOGRAPHY TEMPLATE

APPLICATION NUMBER: 12707365 FILING DATE: 02/17/2010
PATENT NUMBER: 7910042 ISSUE DATE: 03/22/2011
TITLE: CAPILLARY IMPRINTING TECHNIQUE

APPLICATION NUMBER: 12762658 FILING DATE: 04/19/2010
PATENT NUMBER: 7943081 ISSUE DATE: 05/17/2011
TITLE: STEP AND REPEAT IMPRINT LITHOGRAPHY PROCESSES

APPLICATION NUMBER: 10375817 FILING DATE: 02/27/2003
PATENT NUMBER: 7452574 ISSUE DATE: 11/18/2008
TITLE: METHOD TO REDUCE ADHESION BETWEEN A POLYMERIZABLE LAYER AND A SUBSTRATE EMPLOYING A FLUORINE-CONTAINING LAYER

APPLICATION NUMBER: 12946063 FILING DATE: 11/15/2010
PATENT NUMBER: 7947608 ISSUE DATE: 05/24/2011
TITLE: POSITIVE TONE BI-LAYER METHOD

APPLICATION NUMBER: 10438224 FILING DATE: 05/14/2003
PATENT NUMBER: 6805054 ISSUE DATE: 10/19/2004
TITLE: METHOD, SYSTEM AND HOLDER FOR TRANSFERRING TEMPLATES DURING IMPRINT LITHOGRAPHY PROCESSES

APPLICATION NUMBER: 10396615 FILING DATE: 03/25/2003
PATENT NUMBER: 7179396 ISSUE DATE: 02/20/2007
TITLE: POSITIVE TONE BI-LAYER IMPRINT LITHOGRAPHY METHOD

026842/0929 PAGE 12

APPLICATION NUMBER: 10423642 FILING DATE: 04/25/2003
PATENT NUMBER: 7396475 ISSUE DATE: 07/08/2008
TITLE: METHOD OF FORMING STEPPED STRUCTURES EMPLOYING IMPRINT LITHOGRAPHY

APPLICATION NUMBER: 10437476 FILING DATE: 05/14/2003
PATENT NUMBER: 6951173 ISSUE DATE: 10/04/2005
TITLE: ASSEMBLY AND METHOD FOR TRANSFERRING IMPRINT LITHOGRAPHY TEMPLATES

APPLICATION NUMBER: 10645306 FILING DATE: 08/21/2003
PATENT NUMBER: 7442336 ISSUE DATE: 10/28/2008
TITLE: CAPILLARY IMPRINTING TECHNIQUE

APPLICATION NUMBER: 10614716 FILING DATE: 07/07/2003
PATENT NUMBER: 7179079 ISSUE DATE: 02/20/2007
TITLE: CONFORMING TEMPLATE FOR PATTERNING LIQUIDS DISPOSED ON SUBSTRATES

APPLICATION NUMBER: 10616294 FILING DATE: 07/09/2003
PATENT NUMBER: 7150622 ISSUE DATE: 12/19/2006
TITLE: SYSTEMS FOR MAGNIFICATION AND DISTORTION CORRECTION FOR IMPRINT LITHOGRAPHY PROCESSES

APPLICATION NUMBER: 10898034 FILING DATE: 07/23/2004
PATENT NUMBER: 7531025 ISSUE DATE: 05/12/2009
TITLE: METHOD OF CREATING A TURBULENT FLOW OF FLUID BETWEEN A MOLD AND A SUBSTRATE

APPLICATION NUMBER: 10898037 FILING DATE: 07/23/2004
PATENT NUMBER: 7270533 ISSUE DATE: 09/18/2007
TITLE: SYSTEM FOR CREATING A TURBULENT FLOW OF FLUID BETWEEN A MOLD AND A SUBSTRATE

APPLICATION NUMBER: 11695469 FILING DATE: 04/02/2007
PATENT NUMBER: 7768624 ISSUE DATE: 08/03/2010
TITLE: METHOD FOR OBTAINING FORCE COMBINATIONS FOR TEMPLATE DEFORMATION USING NULLSPACE AND METHODS OPTIMIZATION TECHNIQUES

APPLICATION NUMBER: 12392663 FILING DATE: 02/25/2009
PATENT NUMBER: 7815824 ISSUE DATE: 10/19/2010
TITLE: REAL TIME IMPRINT PROCESS DIAGNOSTICS FOR DEFECTS

APPLICATION NUMBER: 10687562 FILING DATE: 10/16/2003
PATENT NUMBER: 7261830 ISSUE DATE: 08/28/2007
TITLE: APPLYING IMPRINTING MATERIAL TO SUBSTRATES EMPLOYING ELECTROMAGNETIC FIELDS

APPLICATION NUMBER: 10677639 FILING DATE: 10/02/2003
PATENT NUMBER: 7090716 ISSUE DATE: 08/15/2006
TITLE: SINGLE PHASE FLUID IMPRINT LITHOGRAPHY METHOD

APPLICATION NUMBER: 10463396 FILING DATE: 06/17/2003
PATENT NUMBER: 7157036 ISSUE DATE: 01/02/2007
TITLE: METHOD TO REDUCE ADHESION BETWEEN A CONFORMABLE REGION AND A PATTERN OF A MOLD

APPLICATION NUMBER: 10694284 FILING DATE: 10/27/2003
PATENT NUMBER: 7122482 ISSUE DATE: 10/17/2006
TITLE: METHODS FOR FABRICATING PATTERNED FEATURES UTILIZING IMPRINT LITHOGRAPHY

MARY BENTON, EXAMINER
ASSIGNMENT SERVICES BRANCH
PUBLIC RECORDS DIVISION

PATENT ASSIGNMENT

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SUBMISSION TYPE:	NEW ASSIGNMENT
NATURE OF CONVEYANCE:	ASSIGNMENT

CONVEYING PARTY DATA

Name	Execution Date
Molecular Imprints, Inc.	09/01/2011

RECEIVING PARTY DATA

Name:	Canon Inc.
Street Address:	30-2 Shimomaruko 3-chome
City:	Ohta-ku, Tokyo
State/Country:	JAPAN
Postal Code:	146-8501

PROPERTY NUMBERS Total: 110

Property Type	Number
Patent Number:	7136150
Patent Number:	7140861
Patent Number:	7019835
Patent Number:	7785526
Patent Number:	7122079
Patent Number:	7323130
Patent Number:	7309225
Patent Number:	7105452
Patent Number:	7252715
Patent Number:	7036389
Patent Number:	6982783
Patent Number:	7244386
Patent Number:	7252777
Patent Number:	7041604
Patent Number:	7256131

Patent Number:	7282550
Patent Number:	7939131
Patent Number:	6990870
Patent Number:	7241395
Patent Number:	7547504
Patent Number:	7186656
Patent Number:	7205244
Patent Number:	7635445
Patent Number:	7292326
Patent Number:	7630067
Patent Number:	7798801
Patent Number:	7636999
Patent Number:	7170589
Patent Number:	7811505
Patent Number:	7281919
Patent Number:	7307118
Patent Number:	7298456
Patent Number:	7338275
Patent Number:	7727453
Patent Number:	7420654
Patent Number:	7316554
Patent Number:	7665981
Patent Number:	7387508
Patent Number:	7803308
Patent Number:	7259102
Patent Number:	7759407
Patent Number:	7670534
Patent Number:	7837921
Patent Number:	7279113
Patent Number:	7357876
Patent Number:	7906058
Patent Number:	7224443
Patent Number:	7037639
Patent Number:	7261831
Patent Number:	7906180

	7491637
Patent Number:	7691313
Patent Number:	7670529
Patent Number:	7670530
Patent Number:	7323417
Patent Number:	7635263
Patent Number:	7699598
Patent Number:	7780893
Patent Number:	7547398
Patent Number:	7462028
Patent Number:	7802978
Patent Number:	7854867
Patent Number:	7641840
Patent Number:	7473090
Patent Number:	6926929
Patent Number:	7670953
Patent Number:	7906274
Patent Number:	7837907
Patent Number:	6932934
Patent Number:	7845931
Patent Number:	7077992
Patent Number:	6900881
Patent Number:	7708926
Patent Number:	7795132
Patent Number:	6908861
Patent Number:	7071088
Patent Number:	7027156
Patent Number:	7070405
Patent Number:	6916584
Patent Number:	6936194
Patent Number:	6871558
Patent Number:	7785096
Patent Number:	7927541
Patent Number:	6929762
Patent Number:	7019819

	7880872
Patent Number:	7874831
Patent Number:	6980282
Patent Number:	7931846
Patent Number:	7858528
Patent Number:	7132225
Patent Number:	7910042
Patent Number:	7943081
Patent Number:	7452574
Patent Number:	7947608
Patent Number:	6805054
Patent Number:	7179396
Patent Number:	7396475
Patent Number:	6951173
Patent Number:	7442336
Patent Number:	7179079
Patent Number:	7150622
Patent Number:	7531025
Patent Number:	7270533
Patent Number:	7768624
Patent Number:	7815824
Patent Number:	7261830
Patent Number:	7090716
Patent Number:	7157036
Patent Number:	7122482

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